PCT

(30) Priority Data: 09/212,776

WORLD INTELLECTUAL PROPERTY ORGANIZATION International Bureau



INTERNATIONAL APPLICATION PUBLISHED UNDER THE PATENT COOPERATION TREATY (PCT)

(51) International Patent Classification 7:		(11) International Publication Number:	WO 00/35603
B05D 7/24	A1	(43) International Publication Date:	22 June 2000 (22.06.00)

US

(21) International Application Number: PCT/US99/30070

16 December 1998 (16.12.98)

(22) International Filing Date: 15 December 1999 (15.12.99)

(71) Applicant: BATTELLE MEMORIAL INSTITUTE [US/US];
Pacific Northwest Division, Intellectual Property Services,
P.O. Box 999, Richland, WA 99352 (US).

(72) Inventor: AFFINITO, John, D.; 2718 Kyle Road, Kennewick, WA 99338 (US).

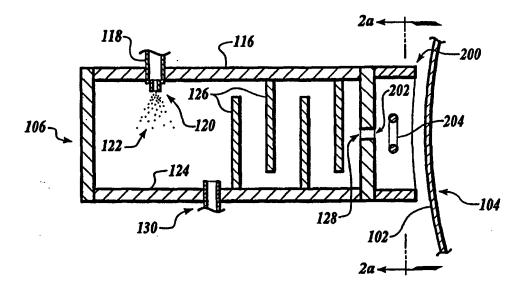
(74) Agent: MAY, Stephen, R.; Battelle Memorial Institute, Pacific Northwest Division, Intellectual Property Services, P.O. Box 999, MSIN: K1-53, Richland, WA 99352 (US). (81) Designated States: JP, KR, European patent (AT, BE, CH, CY, DE, DK, ES, FI, FR, GB, GR, IE, IT, LU, MC, NL, PT, SE).

Published

With international search report.

Before the expiration of the time limit for amending the claims and to be republished in the event of the receipt of amendments.

(54) Title: PLASMA ENHANCED CHEMICAL DEPOSITION FOR HIGH AND/OR LOW INDEX OF REFRACTION POLYMERS



(57) Abstract

The method of the present invention for making a polymer layer with a selected index of refraction has the steps of (a) flash evaporating a monomer material in an evaporate outlet forming an evaporate; (b) passing the evaporate to a glow discharge electrode creating a glow discharge monomer plasma from the evaporate; and (d) cryocondensing the glow discharge monomer plasma on a substrate and crosslinking the glow discharge monomer plasma thereon, wherein the crosslinking results from radicals created in the glow discharge monomer plasma and achieves self curing.

FOR THE PURPOSES OF INFORMATION ONLY

Codes used to identify States party to the PCT on the front pages of pamphlets publishing international applications under the PCT.

AL	Albania	ES	Spain	LS	Lesotho	SI	Slovenia
AM	Armenia	FI	Finland	LT	Lithuania	SK	Slovakia
AT	Austria	FR	Prance	LU	Luxembourg	SN	Senegal
AU	Australia	GA	Gabon	LV	Latvia	SZ	Swaziland
ΑZ	Azerbaijan	GB	United Kingdom	MC	Monaco	TD	Chad
BA	Bosnia and Herzegovina	GE	Georgia	MD	Republic of Moldova	TG	Togo
BB	Barbados	GH	Ghana	MG	Madagascar	TJ	Tajikistan
BE	Belgium	GN	Guinea	MK	The former Yugoslav	TM	Turkmenistan
BF	Burkina Faso	GR	Greece		Republic of Macedonia	TR	Turkey
BG	Bulgaria	HU	Hungary	ML	Mali	TT	Trinidad and Tobago
BJ	Benin	IE	Ireland	MN	Mongolia	UA	Ukraine
BR	Brazil	IL	Israel	MR	Mauritania	UG	Uganda
BY	Belarus	IS	Iceland	MW	Malawi	US	United States of Americ
CA	Canada	IT	Italy	MX	Mexico	UZ	Uzbekistan
CF	Central African Republic	JР	Japan	NE	Niger	VN	Viet Nam
CG	Congo	KE	Kenya	NL	Netherlands	YU	Yugoslavia
CH	Switzerland	KG	Kyrgyzstan	NO	Norway	ZW	Zimbabwe
CI	Côte d'Ivoire	KP	Democratic People's	NZ	New Zealand		
CM	Cameroon		Republic of Korea	PL	Poland		
CN	China	KR	Republic of Korea	PT	Portugal		
CU	Cuba	KZ	Kazakstan	RO	Romania		
CZ	Czech Republic	LC	Saint Lucia	RU	Russian Federation		
DE	Germany	LI	Liechtenstein	SD	Sudan		
DK	Denmark	LK	Sri Lanka	SE	Sweden		
EE	Estonia	LR	Liberia	SG	Singapore		

PLASMA ENHANCED CHEMICAL DEPOSITION FOR HIGH AND/OR LOW INDEX OF REFRACTION POLYMERS

5

10

15

FIELD OF THE INVENTION

The present invention relates generally to a method of making plasma polymerized films having a specified index of refraction. More specifically, the present invention relates to selecting certain monomers to obtain a desired index of refraction of a plasma polymerized polymer film via plasma enhanced chemical deposition with a flash evaporated feed source of a low vapor pressure compound.

As used herein, the term "(meth)acrylic" is defined as "acrylic or methacrylic". Also, "(meth)acyrlate" is defined as "acrylate or methacrylate".

As used herein, the term "cryocondense" and forms thereof refers to the physical phenomenon of a phase change from a gas phase to a liquid phase upon the gas contacting a surface having a temperature lower than a dew point of the gas.

BACKGROUND OF THE INVENTION

20

25

30

The basic process of plasma enhanced chemical vapor deposition (PECVD) is described in THIN FILM PROCESSES, J.L. Vossen, W. Kern, editors, Academic Press, 1978, Part IV, Chapter IV - 1 Plasma Deposition of Inorganic Compounds, Chapter IV - 2 Glow Discharge Polymerization, herein incorporated by reference. Briefly, a glow discharge plasma is generated on an electrode that may be smooth or have pointed projections. Traditionally, a gas inlet introduces high vapor pressure monomeric gases into the plasma region wherein radicals are formed so that upon subsequent collisions with the substrate, some of the radicals in the monomers chemically bond or cross link (cure) on the substrate. The high vapor pressure monomeric gases include gases of CH₄, SiH₄, C₂H₆, C₂H₂, or gases generated from high vapor pressure liquid, for example styrene (10 torr at 87.4 EF (30.8 EC)), hexane (100 torr at

60.4 EF (15.8 EC)), tetramethyldisiloxane (10 torr at 82.9 EF (28.3 EC) 1,3,-dichlorotetra-methyldisiloxane) and combinations thereof that may be evaporated with mild controlled heating. Because these high vapor pressure monomeric gases do not readily cryocondense at ambient or elevated temperatures, deposition rates are low (a few tenths of micrometer/min maximum) relying on radicals chemically bonding to the surface of interest instead of cryocondensation. Remission due to etching of the surface of interest by the plasma competes with the reactive deposition. Lower vapor pressure species have not been used in PECVD because heating the higher molecular weight monomers to a temperature sufficient to vaporize them generally causes a reaction prior to vaporization, or metering of the gas becomes difficult to control, either of which is inoperative.

.10

15

20

25

30

The basic process of flash evaporation is described in U.S. patent 4,954,371 herein incorporated by reference. This basic process may also be referred to as polymer multi-layer (PML) flash evaporation. Briefly, a radiation polymerizable and/or cross linkable material is supplied at a temperature below a decomposition temperature and polymerization temperature of the material. The material is atomized to droplets having a droplet size ranging from about 1 to about 50 microns. An ultrasonic atomizer is generally used. The droplets are then flash vaporized, under vacuum, by contact with a heated surface above the boiling point of the material, but below the temperature which would cause pyrolysis. The vapor is cryocondensed on a substrate then radiation polymerized or cross linked as a very thin polymer layer.

The material may include a base monomer or mixture thereof, cross-linking agents and/or initiating agents. A disadvantage of the flash evaporation is that it requires two sequential steps, cryocondensation followed by curing or cross linking, that are both spatially and temporally separate.

According to the state of the art of making plasma polymerized films, PECVD and flash evaporation or glow discharge plasma deposition and flash evaporation have not been used in combination. However, plasma treatment of a substrate using glow discharge plasma generator with inorganic compounds has been used in combination with flash evaporation under a low pressure

(vacuum) atmosphere as reported in J.D. Affinito, M.E. Gross, C.A., Coronado, and P.M. Martin, A Vacuum Deposition Of Polymer Electrolytes On Flexible Substrates. "Paper for Plenary talk in A Proceedings of the Ninth International Conference on Vacuum Web Coating", November 1995 ed R. Bakish, Bakish Press 1995, pg 20-36., and as shown in FIG. 1a. In that system, the plasma generator 100 is used to etch the surface 102 of a moving substrate 104 in preparation to receive the monomeric gaseous output from the flash evaporation 106 that cryocondenses on the etched surface 102 and is then passed by a first curing station (not shown), for example electron beam or ultra-violet radiation, to initiate cross linking and curing. The plasma generator 100 has a housing 108 with a gas inlet 110. The gas may be oxygen, nitrogen, water or an inert gas, for example argon, or combinations thereof. Internally, an electrode 112 that is smooth or having one or more pointed projections 114 produces a glow discharge and makes a plasma with the gas which etches the surface 102. The flash evaporator 106 has a housing 116, with a monomer inlet 118 and an atomizing nozzle 120, for example an ultrasonic atomizer. Flow through the nozzle 120 is atomized into particles or droplets 122 which strike the heated surface 124 whereupon the particles or droplets 122 are flash evaporated into a gas that flows past a series of baffles 126 (optional) to an outlet 128 and cryocondenses on the surface 102. Although other gas flow distribution arrangements have been used, it has been found that the baffles 126 provide adequate gas flow distribution or uniformity while permitting ease of scaling up to large surfaces 102. A curing station (not shown) is located downstream of the flash evaporator 106.

10

15

20

25

30

In all of these prior art methods, the starting monomer is a (meth)acrylate monomer (FIG. 1b). When R_1 is hydrogen (H), the compound is an acrylate and when R_1 is a methyl group (CH₃), the compound is a methacrylate.

It is known that the monomer composition may be varied to selectively obtain a desired refractive index. Acrylated or methacrylated hydrocarbon chain compositions provide indices of refraction tightly grouped about 1.5. Bisphenyl A diacrylate has an index of refraction of 1.53. Degree of conjugation (number of carbon to carbon double or triple bonds or aromatic rings) generally increases

index of refraction. For example, polyvinylcarbizone has an index of refraction of 2.1 or higher. However, multi-ring system compounds that are solids are not useful as a monomer in these systems. Addition of bromine may increase index of refraction as high as 1.7. Addition of fluorine may reduce index of refraction to as low as 1.3. However, bromine adds a brown color and tends to oxidize over time and fluorinated monomers have high vapor pressures, poor adhesion and high cost.

5

10

15

20

25

30

Therefore, there is a need for an apparatus and method for making plasma polymerized polymer layers at a fast rate but that is also self curing, and with selective index of refraction.

SUMMARY OF THE INVENTION

The present invention is an improved method of plasma polymerization wherein a monomer capable of providing a polymer with a desired index of refraction is cured during plasma polymerization.

The present invention may be (1) an apparatus and method for plasma enhanced chemical vapor deposition of low vapor pressure monomer or a mixture of monomer with particle materials onto a substrate, or (2) an apparatus and method for making self-curing polymer layers, especially self-curing PML polymer layers. From both points of view, the invention is a combination of flash evaporation with plasma enhanced chemical vapor deposition (PECVD) that provides the unexpected improvements of permitting use of low vapor pressure monomer materials in a PEDVD process and provides a self curing from a flash evaporation process, at a rate surprisingly faster than standard PECVD deposition rates.

Generally, the apparatus of the present invention is (a) a flash evaporation housing with a monomer atomizer for making monomer droplets, heated evaporation surface for making an evaporate from the monomer droplets, and an evaporate outlet, (b) a glow discharge electrode downstream of the evaporate outlet for creating a glow discharge plasma from the evaporate, wherein (c) the substrate is proximate the glow discharge plasma for receiving

and cryocondensing the glow discharge plasma thereon. All components are preferably within a low pressure (vacuum) chamber.

The method of the present invention has the steps of (a) flash evaporating a liquid monomer an evaporate outlet forming an evaporate; (b) passing the evaporate to a glow discharge electrode creating a glow discharge monomer plasma from the evaporate; and (c) cryocondensing the glow discharge monomer plasma on a substrate and crosslinking the glow discharge monomer plasma thereon, wherein the crosslinking results from radicals created in the glow discharge plasma and achieves self curing.

It is an object of the present invention to provide a method of making a polymer with a selected index of refraction.

An advantage of the present invention is that it is insensitive to a direction of motion of the substrate because the deposited monomer layer is self curing. Another advantage of the present invention is that multiple layers of materials may be combined. For example, as recited in U.S. patents 5,547,508 and 5,395,644, 5,260,095, hereby incorporated by reference, multiple polymer layers, alternating layers of polymer and metal, and other layers may be made with the present invention in the vacuum environment.

The subject matter of the present invention is particularly pointed out and distinctly claimed in the concluding portion of this specification. However, both the organization and method of operation, together with further advantages and objects thereof, may best be understood by reference to the following detailed description in combination with the drawings wherein like reference characters refer to like elements.

25

30

10

15

20

BRIEF DESCRIPTION OF THE DRAWINGS

FIG. 1a is a cross section of a prior art combination of a glow discharge plasma generator with inorganic compounds with flash evaporation.

FIG. 1b is a chemical diagram of (meth)acrylate.

FIG. 2 is a cross section of the apparatus of the present invention of combined flash evaporation and glow discharge plasma deposition.

FIG. 2a is a cross section end view of the apparatus of the present invention.

FIG. 3 is a cross section of the present invention wherein the substrate is the electrode.

FIG. 4 is a chemical diagram of phenylacetylene and two plasma polymerization routes from phenylacetylene to conjugated polymer.

FIG. 5a is a chemical diagram of triphynyl diamine derivitive

FIG. 5b is a chemical diagram of quinacridone

FIG. 6a is a chemical diagram of diallyldiphenylsilane

FIG. 6b is a chemical diagram of polydiallylphenylsilane

FIG. 7a is a chemical diagram of divinyltetramethyldisiloxane

FIG. 7b is a chemical diagram of vinyltriethoxysilane

DESCRIPTION OF THE PREFERRED EMBODIMENT(S)

15

20

30

10

5

According to the present invention, the apparatus is shown in FIG. 2. The apparatus and method of the present invention are preferably within a low pressure (vacuum) environment or chamber. Pressures preferably range from about 10⁻¹ torr to 10⁻⁶ torr. The flash evaporator 106 has a housing 116, with a monomer inlet 118 and an atomizing nozzle 120. Flow through the nozzle 120 is atomized into particles or droplets 122 which strike the heated surface 124 whereupon the particles or droplets 122 are flash evaporated into a gas or evaporate that flows past a series of baffles 126 to an evaporate outlet 128 and cryocondenses on the surface 102. Cryocondensation on the baffles 126 and other internal surfaces is prevented by heating the baffles 126 and other surfaces to a temperature in excess of a cryocondensation temperature or dew point of the evaporate. Although other gas flow distribution arrangements have been used, it has been found that the baffles 126 provide adequate gas flow distribution or uniformity while permitting ease of scaling up to large surfaces 102. The evaporate outlet 128 directs gas toward a glow discharge electrode 204 creating a glow discharge plasma from the evaporate. In the embodiment shown in FIG. 2, the glow discharge electrode 204 is placed in a glow discharge

housing 200 having an evaporate inlet 202 proximate the evaporate outlet 128. In this embodiment, the glow discharge housing 200 and the glow discharge electrode 204 are maintained at a temperature above a dew point of the evaporate. By controlling a glow discharge parameter of power, voltage or a combination thereof, multiple carbon carbon bonds (double, triple or radical bonds) of the molecules within the evaporate are altered (usually broken to a lower number bond) thereby obtaining a faster reaction rate than for molecules having only single bonds.

10

15

20

25

30

The glow discharge plasma exits the glow discharge housing 200 and cryocondenses on the surface 102 of the substrate 104. It is preferred that the substrate 104 is kept at a temperature below a dew point of the evaporate, preferably ambient temperature or cooled below ambient temperature to enhance the cryocondensation rate. In this embodiment, the substrate 104 is moving and may be electrically grounded, electrically floating, or electrically biased with an impressed voltage to draw charged species from the glow discharge plasma. If the substrate 104 is electrically biased, it may even replace the electrode 204 and be, itself, the electrode which creates the glow discharge plasma from the monomer gas. Electrically floating means that there is no impressed voltage although a charge may build up due to static electricity or due to interaction with the plasma.

A preferred shape of the glow discharge electrode 204, is shown in FIG. 2a. In this preferred embodiment, the glow discharge electrode 204 is separate from the substrate 104 and shaped so that evaporate flow from the evaporate inlet 202 substantially flows through an electrode opening 206. Any electrode shape can be used to create the glow discharge, however, the preferred shape of the electrode 204 does not shadow the plasma from the evaporate issuing from the outlet 202 and its symmetry, relative to the monomer exit slit 202 and substrate 104, provides uniformity of the evaporate vapor flow to the plasma across the width of the substrate while uniformity transverse to the width follows from the substrate motion.

The spacing of the electrode **204** from the substrate **104** is a gap or distance that permits the plasma to impinge upon the substrate. This distance

that the plasma extends from the electrode will depend on the evaporate species, electrode **204**/substrate **104** geometry, electrical voltage and frequency, and pressure in the standard way as described in detail in ELECTRICAL DISCHARGES IN GASSES, F.M. Penning, Gordon and Breach Science Publishers, 1965, and summarized in THIN FILM PROCESSES, J.L. Vossen, W. Kern, editors, Academic Press, 1978, Part II, Chapter II-1, Glow Discharge Sputter Deposition, both hereby incorporated by reference.

10

15

20

25

30

An apparatus suitable for batch operation is shown in FIG. 3. In this embodiment, the glow discharge electrode 204 is sufficiently proximate a part 300 (substrate) that the part 300 is an extension of or part of the electrode 204. Moreover, the part is below a dew point to allow cryocondensation of the glow discharge plasma on the part 300 and thereby coat the part 300 with the monomer condensate and self cure into a polymer layer. Sufficiently proximate may be connected to, resting upon, in direct contact with, or separated by a gap or distance that permits the plasma to impinge upon the substrate. This distance that the plasma extends from the electrode will depend on the evaporate species, electrode 204/substrate 104 geometry, electrical voltage and frequency, and pressure in the standard way as described in ELECTRICAL DISCHARGES IN GASSES, F.M. Penning, Gordon and Breach Science Publishers, 1965, hereby incorporated by reference. The substrate 300 may be stationary or moving during cryocondensation. Moving includes rotation and translation and may be employed for controlling the thickness and uniformity of the monomer layer cryocondensed thereon. Because the cryocondensation occurs rapidly, within milli-seconds to seconds, the part may be removed after coating and before it exceeds a coating temperature limit.

In operation, either as a method for plasma enhanced chemical vapor deposition of low vapor pressure materials onto a substrate, or as a method for making self-curing polymer layers (especially PML), the method of the invention has the steps of (a) flash evaporating a material forming an evaporate; (b) passing the evaporate to a glow discharge electrode creating a glow discharge monomer plasma from the evaporate; and (c) cryocondensing the glow discharge monomer plasma on a substrate and crosslinking the glow discharge

monomer plasma thereon. The crosslinking results from radicals created in the glow discharge plasma thereby permitting self curing.

The flash evaporating has the steps of flowing a monomer material to an inlet, atomizing the material through a nozzle and creating a plurality of monomer droplets of the monomer liquid as a spray. The spray is directed onto a heated evaporation surface whereupon it is evaporated and discharged through an evaporate outlet.

The evaporate is directed to a glow discharge that is controlled to alter material bonds to obtain a polymer with a desired index of refraction upon condensation and curing.

10

15

20

25

. 30

The liquid material may be any liquid monomer. However, it is preferred that the liquid monomer or liquid have a low vapor pressure at ambient temperatures so that it will readily cryocondense. Preferably, the vapor pressure of the liquid monomer material is less than about 10 torr at 83 °F (28.3 °C), more preferably less than about 1 torr at 83 °F (28.3 °C), and most preferably less than about 10 millitorr at 83 °F (28.3 °C). For monomers of the same chemical family, monomers with low vapor pressures usually also have higher molecular weight and are more readily cryocondensible than higher vapor pressure, lower molecular weight monomers. Liquid monomer includes but is not limited to (meth)acrylate, halogenated alkane, phenylacetylene (FIG. 4) and combinations thereof. Monomers with aromatic rings or monomers with multiple (double or triple) bonds (including conjugated monomer or particle) react faster than monomers with only single bonds.

The particle(s) may be any insoluble or partially insoluble particle type having a boiling point below a temperature of the heated surface in the flash evaporation process. Insoluble particle includes but is not limited to triphenyl diamine derivative (TPD, **FIG. 5a**), quinacridone (QA, **FIG. 5b**) and combinations thereof. The insoluble particles are preferably of a volume much less than about 5000 cubic micrometers (diameter about 21 micrometers) or equal thereto, preferably less than or equal to about 4 cubic micrometers (diameter about 2 micrometers). In a preferred embodiment, the insoluble particles are sufficiently small with respect to particle density and liquid monomer density and viscosity

that the settling rate of the particles within the liquid monomer is several times greater than the amount of time to transport a portion of the particle liquid monomer mixture from a reservoir to the atomization nozzle. It is to be noted that it may be necessary to stir the particle liquid monomer mixture in the reservoir to maintain suspension of the particles and avoid settling.

5

10

15

20

25

30

The mixture of monomer and insoluble or partially soluble particles may be considered a slurry, suspension or emulsion, and the particles may be solid or liquid. The mixture may be obtained by several methods. One method is to mix insoluble particles of a specified size into the monomer. The insoluble particles of a solid of a specified size may be obtained by direct purchase or by making them by one of any standard techniques, including but not limited to milling from large particles, precipitation from solution, melting/spraying under controlled atmospheres, rapid thermal decomposition of precursors from solution as described in U.S. patent 5,652,192 hereby incorporated by reference. The steps of U.S. patent 5,652,192 are making a solution of a soluble precursor in a solvent and flowing the solution through a reaction vessel, pressurizing and heating the flowing solution and forming substantially insoluble particles, then quenching the heated flowing solution and arresting growth of the particles. Alternatively, larger sizes of solid material may be mixed into liquid monomer then agitated, for example ultrasonically, to break the solid material into particles of sufficient size.

Liquid particles may be obtained by mixing an immiscible liquid with the monomer liquid and agitating by ultrasonic or mechanical mixing to produce liquid particles within the liquid monomer. Immiscible liquids include, for example phenylacetylene.

Upon spraying, the droplets may be particles alone, particles surrounded by liquid monomer and liquid monomer alone. Since both the liquid monomer and the particles are evaporated, it is of no consequence either way. It is, however, important that the droplets be sufficiently small that they are completely vaporized. Accordingly, in a preferred embodiment, the droplet size may range from about 1 micrometer to about 50 micrometers.

Materials useful for selective index of refraction (n) include but are not limited to aromatic ring compounds. For example, high index of refraction

material may be obtained from lower index of refraction material as in the plasma alteration of diallyldiphenylsilane (n=1.575) (FIG. 6a) to polydiallylphenylsilane ($1.6 \le n \le 1.65$)(FIG. 6b). Alternatively, a lower index of refraction material may be made from a higher index of refraction material by plasma alteration of 1,3-divinyltetramethyldisiloxane (n =1.412) (FIG. 7a) to vinyltriethoxysilane (n=1.396) (FIG. 7b).

A material that is solid may be suspended in a liquid monomer wherein the material cross links into the liquid monomer to alter the index of refraction. Specifically, for example bi-phenyl may be suspended in any of the herein mentioned liquid monomers (conjugated or not), resulting in phenyl, or multiphenyl including but not limited to bi-phenyl, tri-phenyl and combinations thereof, which are cross linked molecules that increase the index of refraction compared to polymerizing the liquid monomer alone.

10

15

20

25

30

Halogenated alkyl compounds may be useful for obtaining a selected index of refraction. Halogens include but are not limited to fluorine, bromine and combinations thereof.

By using flash evaporation, the material is vaporized so quickly that reactions that generally occur from heating a liquid material to an evaporation temperature simply do not occur. Further, control of the rate of evaporate delivery is strictly controlled by the rate of material delivery to the inlet 118 of the flash evaporator 106.

In addition to the evaporate from the material, additional gases may be added within the flash evaporator 106 through a gas inlet 130 upstream of the evaporate outlet 128, preferably between the heated surface 124 and the first baffle 126 nearest the heated surface 124. Additional gases may be organic or inorganic for purposes included but not limited to ballast, reaction and combinations thereof. Ballast refers to providing sufficient molecules to keep the plasma lit in circumstances of low evaporate flow rate. Reaction refers to chemical reaction to form a compound different from the evaporate. Additional gases include but are not limited to group VIII of the periodic table, hydrogen, oxygen, nitrogen, chlorine, bromine, polyatomic gases including for example carbon dioxide, carbon monoxide, water vapor, and combinations thereof.

Alternative Embodiments

The method of the present invention may obtain a polymer layer either by radiation curing or by self curing. In radiation curing (**FIG. 1**), the monomer liquid may include a photoinitiator. In self curing, a combined flash evaporator, glow discharge plasma generator is used without either the e-beam gun or ultraviolet light.

CLOSURE

10

15

While a preferred embodiment of the present invention has been shown and described, it will be apparent to those skilled in the art that many changes and modifications may be made without departing from the invention in its broader aspects. The appended claims are therefore intended to cover all such changes and modifications as fall within the true spirit and scope of the invention.

I claim:

10

15

20

25

1. A method of making a polymer layer having a selected index of refraction, the method using plasma enhanced chemical vapor deposition onto a substrate in a vacuum environment, comprising the steps of:

- (a) providing a monomer cross linkable into a polymer with said selected index of refraction;
- (b) making an evaporate by receiving into a flash evaporation housing, evaporating said monomer on an evaporation surface, and discharging an evaporate through an evaporate outlet;
- (c) making a monomer plasma from said evaporate by passing said evaporate proximate a glow discharge electrode and creating a glow discharge for making said plasma from the evaporate; and
- (d) condensing and crosslinking said monomer plasma onto said substrate and forming said polymer layer having said selected index of refraction.
- 2. The method as recited in claim 1, wherein the substrate is proximate the glow discharge electrode and is electrically biased with an impressed voltage, receiving the monomer plasma cryocondensing thereon.
 - 3. The method as recited in claim 1, wherein said glow discharge electrode is positioned within a glow discharge housing having an evaporate inlet proximate the evaporate outlet, said glow discharge housing and said glow discharge electrode maintained at a temperature above a dew point of said evaporate and said substrate is downstream of said monomer plasma, electrically floating, receiving the monomer plasma cryocondensing thereon.
- The method as recited in claim 1, wherein the substrate is
 proximate the glow discharge electrode and is electrically grounded, receiving the monomer plasma cryocondensing thereon.

5. The method as recited in claim 1, wherein said monomer is selected from the group consisting of halogenated alkyl, diallyldiphenylsilane, 1,3-divinyltetramethyldisiloxane, phenylacetylene, acrylate, methacrylate, and combinations thereof.

5

- 6. The method as recited in claim 1, wherein said substrate is cooled.
- 7. The method as recited in claim 1, further comprising adding an additional gas.
 - 8. The method as recited in claim 7, wherein said additional gas is a ballast gas.
- 15 9. The method as recited in claim 7, wherein said additional gas is a reaction gas.
 - 10. The method as recited in claim 9, wherein said reaction gas is oxygen gas.

20

11. The method as recited in claim 1, further comprising particles selected from the group consisting of organic solids, liquids, and combinations thereof.

25

30

- 12. The method as recited in claim 11, wherein the organic solids are selected from the group consisting of biphenyl, triphenyl diamine derivitive, quinacridone, and combinations thereof.
- 13. A method for making a polymer layer of a polymer with a selected index of refraction in a vacuum chamber, comprising the steps of:

(a) flash evaporating a monomer material capable of cross linking into said polymer with said selected index of refraction, forming an evaporate;

- (b) passing said evaporate to a glow discharge electrode creating a glow discharge monomer plasma from the evaporate;
- (c) condensing said glow discharge monomer plasma on a substrate and crosslinking said glow discharge plasma thereon, said crosslinking resulting from radicals created in said glow discharge plasma for self curing and forming said polymer layer having said selected index of refraction.

10

5

14. The method as recited in claim 13, wherein the substrate is proximate the glow discharge electrode and is electrically biased with an impressed voltage, receiving the monomer plasma cryocondensing thereon.

15

15. The method as recited in claim 13, wherein said glow discharge electrode is positioned within a glow discharge housing having an evaporate inlet proximate the evaporate outlet, said glow discharge housing and said glow discharge electrode maintained at a temperature above a dew point of said evaporate and said substrate is downstream of said monomer plasma, and electrically floating, receiving the monomer plasma cryocondensing thereon.

20

16. The method as recited in claim 13, wherein the substrate is proximate the glow discharge electrode and is electrically grounded, receiving the monomer plasma cryocondensing thereon.

25

17. The method as recited in claim 13, wherein said monomer material is a conjugated monomer.

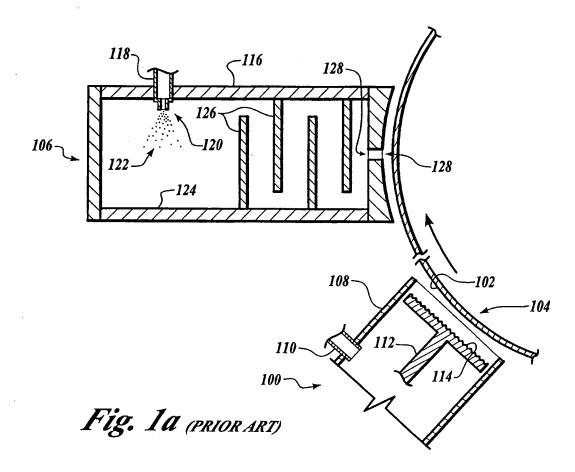
18. The method as recited in claim 13, wherein said monomer is selected from the group consisting of diallyldiphenylsilane, 1,3-divinyltetramethyldisiloxane, phenylacetylene, acrylate, methacrylate and combinations thereof.

19. The method as recited in claim 13, wherein said substrate is cooled.

5 20. The method as recited in claim 13, wherein said material is a monomer containing particles.

10

- 21. The method as recited in claim 20, wherein said monomer is a conjugated monomer.
- 22. The method as recited in claim 20, wherein said particles are selected from the group consisting of organic solids, liquids, and combinations thereof.
- 15 23. The method as recited in claim 22, wherein the organic solids are selected from the group consisting of biphenyl, triphenyl diamine derivitive, quinacridone, and combinations thereof.



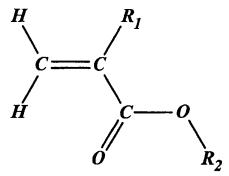
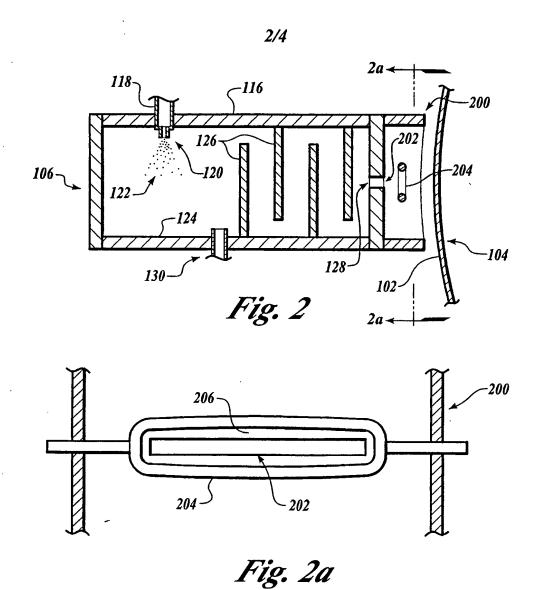
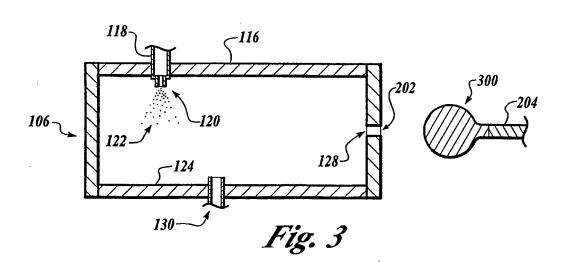


Fig. 1b (PRIOR ART)





INTERNATIONAL SEARCH REPORT

In ational Application No PCT/US 99/30070

	· · · · · · · · · · · · · · · · · · ·			
A. CLASSI IPC 7	FICATION OF SUBJECT MATTER B05D7/24		-	
According to	o International Patent Classification (IPC) or to both national classific	eation and IPC		
	SEARCHED			
Minimum do	ocumentation searched (classification system followed by classificat	ion symbols)		
IPC 7	B05D			
Documenta	tion searched other than minimum documentation to the extent that	such documents are included in the fields s	earched	
Electronic d	lata base consulted during the international search (name of data ba	ase and, where practical, search terms used	i)	
ļ	•			
C. DOCUM	ENTS CONSIDERED TO BE RELEVANT			
Category °	Citation of document, with indication, where appropriate, of the re-	levant passages	Relevant to claim No.	
			Troisvani lo ciami i i co.	
P,X	WO 99 16931 A (BATTELLE MEMORIAL		1-3,	
ĺ	INSTITUTE) 8 April 1999 (1999-04-	-08)	5-10,13,	
			15,	
Υ			18-20,22	
•	the whole document		11,12	
P,Y	WO 99 16557 A (BATTELLE MEMORIAL		11 10	
','	INSTITUTE) 8 April 1999 (1999-04-	-08)	11,12	
	the whole document			
Α	EP 0 340 935 A (SPECTRUM CONTROL	TAIC	1	
^	8 November 1989 (1989-11-08)	INC)	1	
	the whole document			
Funt	her documents are listed in the continuation of box C.	X Patent family members are listed	in annex.	
° Special ca	tegories of cited documents :	"T" later document published after the inte	mational filing date	
"A" docume	ent defining the general state of the art which is not lered to be of particular relevance	or priority date and not in conflict with cited to understand the principle or the	the application but	
"E" earlier d	focument but published on or after the international	invention "X" document of particular relevance; the c	laimed invention	
"L" document which may throw doubts on priority claim(s) or involve an inventive step when the document is taken along				
citation	res estes special (as special)	"Y" document of particular relevance; the c cannot be considered to involve an inv	laimed invention	
"O" docume other n	ent referring to an oral disclosure, use, exhibition or neans	document is combined with one or mo ments, such combination being obvious	re other such docu-	
"P" docume	ent published prior to the international filing date but nan the priority date claimed	in the art. "&" document member of the same patent	·	
	actual completion of the international search	Date of mailing of the international sea		
28	8 April 2000	09/05/2000		
Name and m	nailing address of the ISA	Authorized officer		
	European Patent Office, P.B. 5818 Patentlaan 2 NL – 2280 HV Rijswijk			
	Tel. (+31~70) 340-2040, Tx. 31 651 epo nl, Fax: (+31-70) 340-3016	Brothier, J-A		

INTERNATIONAL SEARCH REPORT

Information on patent family members

In .ational Application No PCT/US 99/30070

Patent document cited in search report	Publication date	Patent family member(s)	Publication date
WO 9916931 A	08-04-1999	NONE	
WO 9916557 A	08-04-1999	US 5902641 A	11-05-1999
EP 0340935 A	08-11-1989	US 4842893 A JP 1316450 A US 5032461 A	27-06-1989 21-12-1989 16-07-1991